

NC-80MAP SEMI-AUTO SHEET RESISTANCE/RESISTIVITY MEASUREMENT

NC-80MAP



- Multi-point, Non-Contact Type by Eddy Current method
- PC controlled via software
- Possible to measure wide range of sheet resistance by installing Maximum of 4 probes
- Minimum 8mm position from edge can be measured
- User programable measurement pattern & measuring pattern
- Option: thickness measurement probe (for silicon wafer)
- Measure Range depends on selected Probe Type
- Sample Size: $\varnothing 2''$ to $\varnothing 8''$ (option $\varnothing 12''$)

MEASURE RANGE

PARAMETER	LOW PROBE TYPE	MIDDLE PROBE TYPE	HIGH PROBE TYPE	S-HIGH PROBE TYPE
RESISTIVITY ($\Omega \cdot \text{cm}$)	0.001 to 0.05	0.05 to 0.5	0.5 to 60.0	60.0 to 200.0
SHEET RESISTANCE (Ω/Sq)	0.01 to 0.5	0.5 to 10.0	10.0 to 1k	1k to 3k

APPLICABLE MATERIALS

- Semiconductor and Solar-cell materials (Silicon, Polysilicon, SiC etc)
- Functional materials (Carbon nanotube, DLC, graphene, Ag nanowire etc)
- Conductive thin film (Metal, ITO etc)
- Diffused sample (or layer)
- Silicon-related epitaxial materials, Ion-implantation sample
- Others: On Request

